



IPW

PATENT  
8045-1015

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Shinichi NAKATA et al.

Conf. 6017

Application No. 10/676,132

Group 1725

Filed October 2, 2003

Examiner Maria A. Elve

MASK FOR LIGHT EXPOSURE AND METHOD  
FOR MANUFACTURING LIQUID CRYSTAL  
DISPLAY APPARATUS EMPLOYING SAME

**RESPONSE**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

January 18, 2006

Sir:

This responds to the Official Action of October 18,  
2005.

**Remarks** begin on page 2 of this paper.